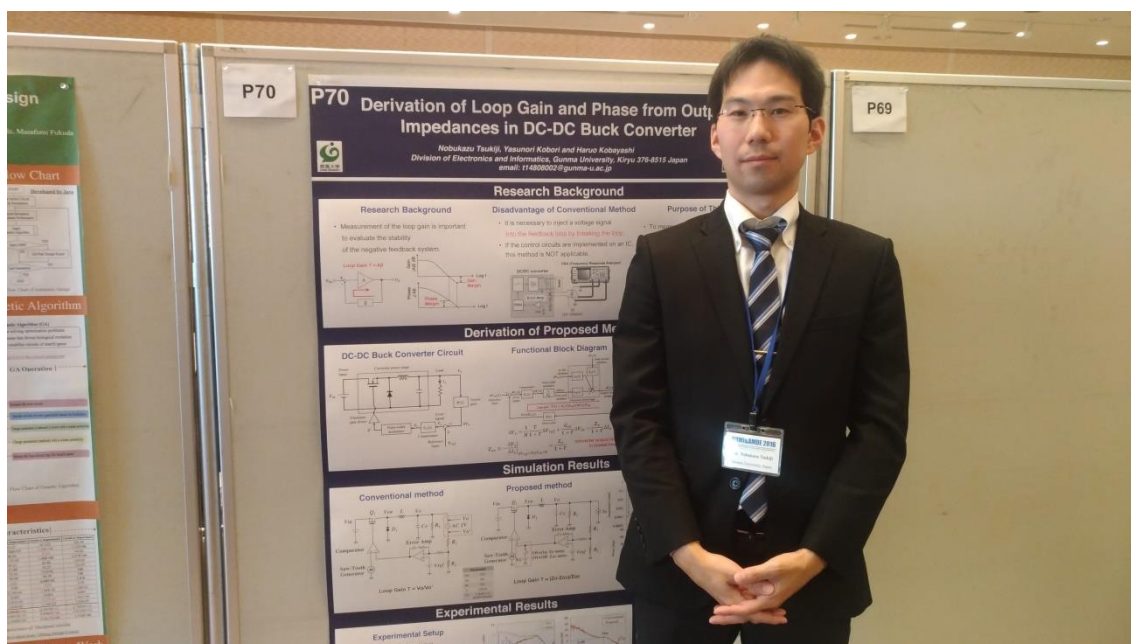
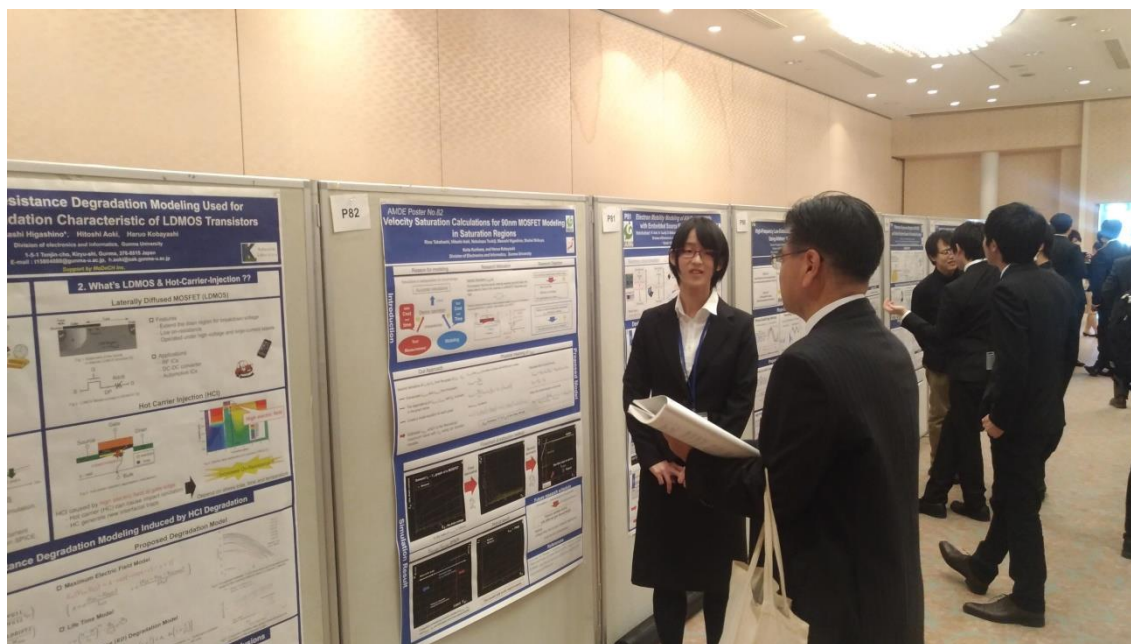
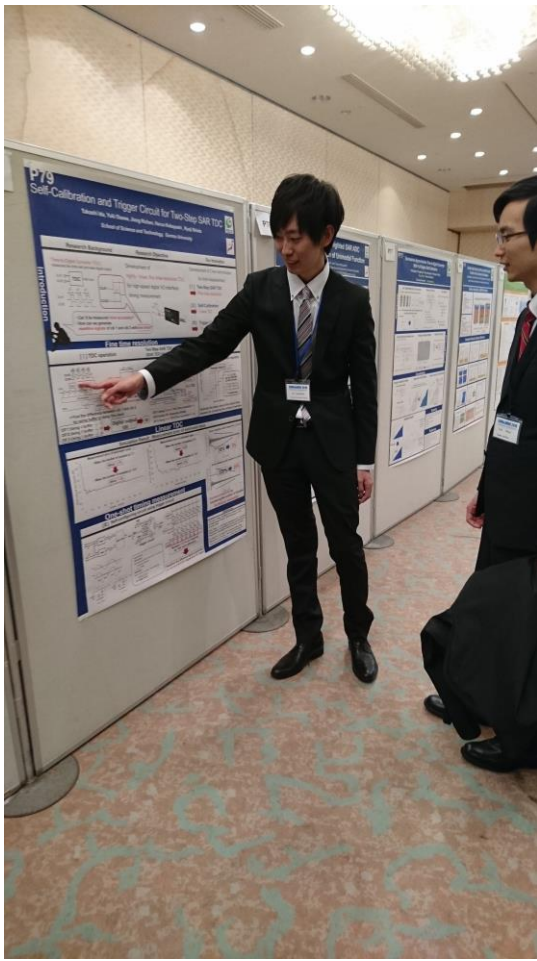


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P81 **Electron Mobility Modeling of AlN/GaN MIS-HEMTs with Embedded Source Field-Plate Structures**

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Introduction

Electronic circuit simulator: Specification → Design → Implementation → Measurement → Evaluation → Simulation → Design → Specification. Need many money & Time... Low cost & speedy.

Device Modeling: Measurement → Modeling → Simulation → Model.

Research Background: Breakdown voltage ↑, Minutization ↓, Switching speed ↑, Circuit Size Large → Small, Circuit Density ↑. Devices characteristic: Normally-ON, Normally-OFF. Application: Communication, Power devices. Research Goal: Research & develop drain current model of normally-off GaN MIS-HEMTs.

Device Structure

1. S, G, D, AIN/GaN layers. MIS gate structure.

2. S, G, D, AIN/GaN layers. Embedded source field-plate structure.

New Electron Mobility Model

New Electron Mobility Model:
$$\mu_{eff} = \frac{\mu_b \cdot U_{eff}}{1 + U_{eff} - U_{SP}}$$

Effective channel length:
$$U_{eff} = 1.0 - UP \cdot e^{-U_{eff}/UP}$$

Gate voltage:
$$U_{gate} = UA \left(\frac{V_{gs} + 2 \cdot V_{th}}{T_{ox}} \right) + UB \left(\frac{V_{gs} + 2 \cdot V_{th}}{T_{ox}} \right)^2$$

Source field plate:
$$U_{SP} = 1 + USFP \cdot V_{ds}$$

Surface:
$$\mu_b = \mu_{b0} \cdot \mu_{sp}$$

Measurement & Simulations

Ids vs Vgs: Saturation region. Log(Ids) vs Vgs.

P83 **Study on ON-Resistance Degradation Modeling Used for HCI Induced Degradation Characteristic of LDMOS Transistors**

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 Support by MoDeCH Inc.

1. Introduction

Background

Reliability Test Problem in Circuit Design

| Test Name | Conditions |
|-----------------------------------|--------------------|
| High Temperature Operating Life | 150~125°C |
| Temperature Humidity Bias | 125°C, 85%RH |
| Temperature Voltage Humidity Bias | 125°C, 85%RH, 100V |

Long testing time and high costs
 Circuit design considering with reliability simulations

Research Objective

Degradation modeling of n-channel LDMOS

- Model derivations for HCI degradation simulation.
 - Maximum electric field model
 - On-resistance degradation model
- Verifications our models with DC drain current simulations by using HISIM-HV model on SPICE.

2. What's LDMOS & Hot-Carrier-Injection ??

Laterally Diffused MOSFET (LDMOS)

Fig. 1. Structure of the bulk lateral LDMOS structure.

Fig. 2. LDMOS Model structure (©2008 MoDeCH Inc.)

Hot Carrier Injection (HCI)

Fig. 3. Hot-carrier injection degradation mechanism.

HCI caused by high electric field at gate edge
 Hot carrier (HC) can cause impact ionization
 HC generate new interfacial traps
 Depend on stress bias, time and temperature

3. ON-Resistance Degradation Modeling Induced by HCI Degradation

HISIM-HV model: On-Resistance

Proposed Degradation Model: Maximum Electric Field Model

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